

[Name of Document] ABSTRACT

A control system comprises a control apparatus 17 that controls a process apparatus 10, which performs a predetermined process on a wafer W, based on plural pieces
5 of process information to be detected in the process apparatus 10, and alarm generation means 21 which generates an alarm when the detected process information is off a predetermined range. The control apparatus 17 grasps the generation state of an alarm, and gives warning when the
10 generation state reaches a predetermined threshold.